

ABSTRACT OF THE DISCLOSURE

Multipurpose holders for electronic components utilized during a fabrication process must allow the components to be submerged into baths of hydrofluoric acid, rinsed in de-ionized water (D.I.), placed into baths of alcohol for dehydration, and ultimately dried prior to further processing. The holders provide both fluid flow around the wafers while in each bath of fluid and while being processed by the critical point dryer, and a containment system to keep the wafer submerged in fluid at all times during the transfer between baths and the drying equipment.

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